

## SiO<sub>2</sub>薄膜的液相沉积及特性

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**摘要:**将基片浸入到低温SiO<sub>2</sub>过饱和的六氟硅酸(H<sub>2</sub>SiF<sub>6</sub>)溶液中,在其表面上沉积SiO<sub>2</sub>薄膜。这种新的生长工艺称之为液相沉积(LPD)。本文着重介绍LPD工艺及LPD SiO<sub>2</sub>薄膜的特性。

**关键词:**液相沉积;SiO<sub>2</sub>;薄膜

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## IPD OF SiO<sub>2</sub> FILM AND ITS PROPERTIES

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**Abstract:**A silica(SiO<sub>2</sub>) film was deposited on the surface of a sub-6 strate by immersing it into hydro-fluosilic acid(H<sub>2</sub>SiF<sub>6</sub>) solution supersaturated with silicagel at low temperature.This process is called liquid phase deposition(LPD).This new LPD process and some properties of the LPD SiO<sub>2</sub> film are presented in this paper.

**Keywords:**liquid phase deposition;SiO<sub>2</sub>;film

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